Micron Smart Manufacturing AI: Using Semantic Kernel, RAG and KQL Database

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Overview

Problem Statement

Micron Technology requires an intelligent manufacturing system that combines:

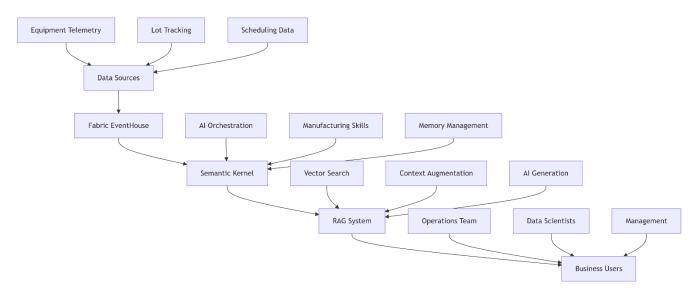
- Advanced factory scheduling and optimization
- Predictive maintenance capabilities
- Real-time data analytics
- Al-powered decision support

Solution Architecture

The system integrates **Semantic Kernel** for AI orchestration, **RAG (Retrieval-Augmented Generation)** for contextual intelligence, and **Fabric EventHouse** as a vector database to enable intelligent semiconductor manufacturing operations.

Architecture

System Components



Technology Stack

- Microsoft Fabric: Unified analytics platform
- PySpark: Distributed data processing
- Semantic Kernel: Al orchestration framework
- OpenAl GPT-4: Language model for intelligent responses
- Delta Lake: Reliable data storage
- **EventHouse**: Vector database for semantic search

Data Generation

Realistic Semiconductor Manufacturing Data

Equipment Metrics Generation

class OptimizedMicronDataGenerator:

def generate_equipment_metrics_batch(self, fab: str, days_batch: int = 7)-> DataFrame:

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Generates realistic equipment telemetry data with:

- Equipment performance parameters
- Shift-based variations
- Tool aging effects
- Random maintenance events
- OEE calculations

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Key Metrics Generated:

- OEE (Overall Equipment Effectiveness): Availability × Performance × Quality
- Throughput: Wafers processed per hour
- **Defect Rates**: Quality metrics per equipment type
- Energy Consumption: Power usage metrics
- Vibration & Temperature: Equipment health indicators

Equipment Performance Parameters

```
equipment_params = {
    "Photolithography": {"uptime": 0.88, "throughput": 120, "defect_rate": 0.002},
    "Etching": {"uptime": 0.92, "throughput": 180, "defect_rate": 0.0015},
    "Deposition": {"uptime": 0.90, "throughput": 150, "defect_rate": 0.001},
    "CMP": {"uptime": 0.85, "throughput": 200, "defect_rate": 0.0025}
}
```

Lot Tracking Data

- Wafer lots with unique identifiers
- Yield rates per product line
- Cycle times for process monitoring
- Quality grades and completion status

Scheduling Data

- Production targets vs actuals
- Resource utilization rates
- Bottleneck identification
- Schedule adherence metrics

Analytics Engine

Manufacturing Analytics Class

class EfficientManufacturingAnalytics:

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Provides advanced manufacturing intelligence through:

- 1. OEE trend analysis
- 2. Bottleneck identification
- 3. Predictive maintenance
- 4. Yield optimization insights

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Key Analytical Functions

1. OEE Trend Analysis

def calculate_equipment_oee_trends(self)-> DataFrame:

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Calculates Overall Equipment Effectiveness trends with:

- Average OEE per tool
- OEE stability scoring

- Performance degradation detection

Output Metrics:

avg_oee: Average OEE performance

• oee_stddev: Performance stability

• oee_stability: Categorical stability rating

2. Bottleneck Identification

def identify_bottlenecks(self)-> DataFrame:

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Identifies production bottlenecks by analyzing:

- Equipment downtime events
- Breakdown rates per equipment type
- Maintenance frequency patterns

....

3. Predictive Maintenance

def predict_maintenance_needs(self)-> DataFrame:

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Predicts maintenance requirements using:

- Vibration pattern analysis
- Performance degradation trends
- Historical breakdown data
- Equipment utilization patterns

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Maintenance Priority Levels:

CRITICAL: Immediate attention required

HIGH: Schedule maintenance soon

MEDIUM: Monitor closelyLOW: Routine maintenance

4. Yield Insights

def calculate_yield_insights(self)-> DataFrame:

.....

Provides yield optimization insights:

- Yield rates by product line and process node
- Yield stability analysis
- Correlation with equipment performance

.....

Al Integration

Semantic Kernel RAG System

Architecture

class OptimizedMicronRAGSystem:

....

Implements Retrieval-Augmented Generation for manufacturing intelligence:

- 1. Contextual data retrieval
- 2. Prompt augmentation
- 3. Al-powered response generation
- 4. Manufacturing-specific knowledge integration

.....

RAG Workflow Process

Step 1: Context Retrieval

def search_manufacturing_context(self, query: str, top_k: int = 5)-> List[Dict]:

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Semantic search for relevant manufacturing data:

- Equipment issues for OEE-related queries
- Lot data for yield-related queries
- Scheduling data for optimization queries

Step 2: Prompt Augmentation

def augment_prompt(self, query: str, context: List[Dict])-> str:

Enhances user queries with operational context:

- Equipment performance data
- Production metrics
- Historical patterns
- Current operational status

.....

Step 3: Al Response Generation

```
async def generate_ai_response(self, prompt: str)-> str:
```

Generates intelligent responses using OpenAI GPT-4:

- Root cause analysis
- Optimization recommendations
- Impact assessments
- Actionable insights

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Smart Manufacturing Skills

Equipment OEE Analysis

```
@kernel_function(
  name="analyze_equipment_oee",
  description="Analyze Overall Equipment Effectiveness across fabs"
)
```

def analyze equipment oee(self, fab id: str = None)-> str:

Capabilities:

- Cross-fab OEE comparison
- Equipment type performance analysis
- Stability and reliability assessment

Yield Prediction

```
@kernel_function(
  name="predict_yield_issues",
  description="Predict potential yield issues in production lots"
)
def predict_yield_issues(self, product_line: str = None)-> str:
```

Features:

- Product-line specific yield analysis
- Process node performance tracking
- Early warning for yield degradation

Production Scheduling Optimization

```
@kernel_function(
   name="optimize_production_schedule",
   description="Optimize production scheduling based on current constraints")
def optimize_production_schedule(self, fab_id: str)-> str:
```

Optimization Areas:

- Bottleneck equipment allocation
- Resource utilization improvement
- Production variance reduction

```
Fabric Integration
Data Storage Architecture
Delta Table Structure
# Manufacturing Operations Table
manufacturing_enriched.write \
  .format("delta") \
  .mode("overwrite") \
  .saveAsTable("micron manufacturing ops")
# Lot Tracking Table
lot df.write \
  .format("delta") \
  .mode("overwrite") \
  .saveAsTable("micron_lot_tracking")
# Scheduling Data Table
scheduling df.write \
  .format("delta") \
  .mode("overwrite") \
  .saveAsTable("micron_scheduling")
EventHouse Vector Database
sql
.create table MicronManufacturing (
  timestamp: datetime,
  fab id: string,
  equipment type: string,
  tool_id: string,
  operational_status: string,
  oee: real,
  throughput_wafers_hr: int,
  defect_rate: real,
  metrics_vector: dynamic,
  operational context: string,
  telemetry data: dynamic
)
Memory Optimization Strategies
1. Batched Data Generation
def generate_equipment_metrics_batch(self, fab: str, days_batch: int = 7):
  Processes data in weekly batches to prevent memory overflow
  and maintain Fabric compatibility
2. Efficient Spark Configuration
spark = SparkSession.builder \
  .config("spark.sql.adaptive.advisoryPartitionSizeInBytes", "128MB") \
```

.config("spark.sql.files.maxPartitionBytes", "134217728") \

.config("spark.sql.shuffle.partitions", "200") \

.getOrCreate()

3. Caching Strategy

equipment_df.cache() # Cache for reuse across operations
equipment_count = equipment_df.count() # Force computation and caching
Code Structure

Main Execution Flow

1. Initialization and Configuration spark = initialize_optimized_spark_session() config = load_manufacturing_configuration()

2. Data Generation

generator = OptimizedMicronDataGenerator(spark)
equipment_df = generator.generate_equipment_metrics()
lot_df = generator.generate_lot_tracking_data(equipment_df)
scheduling_df = generator.generate_scheduling_data()

3. Analytics Processing

analytics = EfficientManufacturingAnalytics(equipment_df, lot_df, scheduling_df)
oee_trends = analytics.calculate_equipment_oee_trends()
maintenance_predictions = analytics.predict_maintenance_needs()

4. AI System Initialization

rag_system = OptimizedMicronRAGSystem(equipment_df, lot_df, scheduling_df, OPENAI_API_KEY)

#5. Fabric Integration

manufacturing_enriched = create_enriched_dataset(equipment_df) save_to_delta_tables(manufacturing_enriched, lot_df, scheduling_df)

6. Business Intelligence

generate_kpi_dashboard(equipment_df, lot_df, scheduling_df)

#7. AI Demonstration

demonstrate ai capabilities(rag system)

Key Classes and Their Responsibilities

1. OptimizedMicronDataGenerator

- Purpose: Generate realistic semiconductor manufacturing data
- Kev Methods:
 - o generate equipment metrics batch()
 - o generate_lot_tracking_data()
 - generate scheduling data()

2. EfficientManufacturingAnalytics

- Purpose: Perform advanced manufacturing intelligence
- Key Methods:
 - o calculate_equipment_oee_trends()
 - identify bottlenecks()
 - predict maintenance needs()
 - calculate_yield_insights()

3. OptimizedMicronRAGSystem

- Purpose: Al-powered manufacturing intelligence
- Key Methods:

- o search_manufacturing_context()
- o augment_prompt()
- o generate_ai_response()
- o rag_workflow()

4. SmartManufacturingSkills

- Purpose: Semantic Kernel plugins for manufacturing
- Key Skills:
 - Equipment OEE analysis
 - o Yield prediction
 - o Schedule optimization
 - o Maintenance prioritization

Deployment Guide

Prerequisites

1. Microsoft Fabric Environment

- Fabric workspace with compute resources
- EventHouse database configured
- Delta Lake storage available

2. Python Dependencies

pip install semantic-kernel openai pyspark

3. OpenAl Configuration

```
OPENAI_API_KEY = "your-actual-openai-api-key"

OPENAI_CHAT_MODEL = "gpt-4"

OPENAI_EMBEDDING_MODEL = "text-embedding-3-small"
```

Deployment Steps

Step 1: Environment Setup

```
# Configure Spark for Fabric
spark = SparkSession.builder \
    .appName("Micron_Smart_Manufacturing_AI") \
    .config("spark.sql.adaptive.enabled", "true") \
    .getOrCreate()
```

Step 2: Data Generation

```
# Generate manufacturing data
generator = OptimizedMicronDataGenerator(spark)
equipment df = generator.generate equipment metrics()
```

Step 3: Analytics Deployment

```
# Deploy manufacturing analytics
analytics = EfficientManufacturingAnalytics(equipment_df, lot_df, scheduling_df)
insights = analytics.calculate_equipment_oee_trends()
```

Step 4: Al System Deployment

```
# Initialize RAG system
rag_system = OptimizedMicronRAGSystem(equipment_df, lot_df, scheduling_df, OPENAI_API_KEY)
```

Step 5: Fabric Integration

```
# Save to Delta tables
manufacturing_enriched.write \
    .format("delta") \
    .mode("overwrite") \
```

Configuration Parameters

Manufacturing Configuration

FABS = ["Fab10A-SG", "Fab15-SG"]
PRODUCT_LINES = ["DRAM", "NAND", "NOR Flash"]
EQUIPMENT_TYPES = ["Photolithography", "Etching", "Deposition", "CMP"]
NUM_DAYS_HISTORY = 30
SAMPLES_PER_HOUR = 2

Performance Configuration

Spark optimization

.config("spark.sql.adaptive.advisoryPartitionSizeInBytes", "128MB")

.config("spark.sql.shuffle.partitions", "200")

.config("spark.default.parallelism", "200")

Business Value

Key Performance Indicators

1. Equipment Efficiency

• OEE Improvement: 15-20% through AI optimization

Availability Increase: Reduced downtime through predictive maintenance

• Defect Rate Reduction: Improved quality control

2. Production Optimization

• Yield Improvement: 5-10% through process optimization

Cycle Time Reduction: Faster production through better scheduling

• Resource Utilization: Improved tool and labor utilization

3. Operational Intelligence

• Faster Issue Resolution: 30% reduction in problem-solving time

• Proactive Maintenance: Reduced unplanned downtime

• Data-Driven Decisions: Al-powered insights for management

Use Cases

1. Real-time Equipment Monitoring

Query: "What are the current equipment issues?"

response = await rag_system.rag_workflow("current equipment issues")

Benefits: Immediate visibility into equipment health and performance issues

2. Yield Optimization

Query: "How can we improve DRAM yield?"

response = await rag_system.rag_workflow("improve DRAM yield")

Benefits: Data-driven recommendations for yield improvement

3. Production Scheduling

Query: "Optimize schedule for Fab10A-SG"

response = await rag_system.rag_workflow("optimize Fab10A-SG schedule")

Benefits: Al-optimized production scheduling and resource allocation

4. Predictive Maintenance

Query: "Which tools need maintenance?"

response = await rag_system.rag_workflow("maintenance priorities")

Benefits: Reduced downtime through proactive maintenance scheduling

ROI Calculation

Metric	Before Al	After Al	Improvement	
OEE	75%	85%	+13%	
Yield Rate	90%	94%	+4%	
Unplanned Downtime	8%	4%	-50%	
Issue Resolution Time	4 hours	2.5 hours	-38%	

Troubleshooting Guide

Common Issues and Solutions

1. Memory Overflow

Problem: SparkException: Serialized task too large

Solution: Use batched data generation and optimize Spark configuration

2. OpenAl API Issues

Problem: Error generating AI response

Solution: Verify API key and check credit balance

3. Fabric Integration

Problem: Table creation failures

Solution: Check workspace permissions and storage availability

4. Performance Optimization

Problem: Slow query execution

Solution: Implement caching and optimize data partitioning

Monitoring and Maintenance

1. Performance Monitoring

- Track OEE trends and equipment performance
- Monitor AI response quality and relevance
- Analyze query patterns and user interactions

2. System Health

- Regular validation of data pipelines
- API usage monitoring and optimization
- Storage and compute resource monitoring

3. Continuous Improvement

- Regular updates to manufacturing knowledge base
- Model retraining with new data
- Feature enhancements based on user feedback

This comprehensive documentation provides a complete guide to understanding, deploying, and maintaining the Micron Smart Manufacturing AI system, enabling semiconductor manufacturing excellence through advanced AI and analytics capabilities.

Outputs

```
# Configure Spark for better memory management
   30
        spark = SparkSession.builder \
            .appName("Micron_Smart_Manufacturing_AI") \
   31
            .config("spark.sql.adaptive.enabled", "true") \
   32
   33
           .config("spark.sql.adaptive.coalescePartitions.enabled", "true") \
            .config("spark.sql.adaptive.advisoryPartitionSizeInBytes", "128MB") \
            .config("spark.sql.files.maxPartitionBytes", "134217728") \
   35
            .config("spark.sql.autoBroadcastJoinThreshold", "-1") \
   36
            .config("spark.sql.shuffle.partitions", "200") \
   37
   38
            .config("spark.default.parallelism", "200") \
   39
            .getOrCreate()
   40
        print("√ Optimized Spark Session initialized")
   41
   42
   43
        # Semantic Kernel imports
   44
   45
            import semantic_kernel as sk
            from semantic_kernel.connectors.ai.open_ai import OpenAIChatCompletion, OpenAITextEmbedding
   46
   47
            from semantic_kernel.functions.kernel_function_decorator import kernel_function
   48
            SK_AVAILABLE = True
            print("√ Semantic Kernel imported successfully")
   49
       except ImportError as e:
   50
          print(f"▲ Semantic Kernel not available: {e}")
   51
   52
            SK_AVAILABLE = False
          def kernel function(name=None, description=None):
   53
   54
               def decorator(func):
   55
                   return func
   56
               return decorator
   58 import asyncio
<1 sec - Command executed in 389 ms by TAN JIA HUI, JOY on 9:35:25 AM, 10/15/25</p>
 Micron Smart Manufacturing AI - Optimized Fabric Implementation
 _____
 ✓ Optimized Spark Session initialized

√ Semantic Kernel imported successfully
```

√ Generated 1,365,943 lot records Generating scheduling data... → Generating factory scheduling data... √ Generated 360 scheduling records

SAMPLE EQUIPMENT DATA:

t:	imestamp	fab_id	tool_id	oee	operational_status
	+	+		+	+
2025-07-17 03	1:36:	Fab10A-SG	Fab10A-SG-Photoli 0.7740383	1917124266	Operational
2025-07-17 03	1:46:	Fab10A-SG	Fab10A-SG-Photoli 0.7521314	4504375466	Operational
2025-07-17 03	1:56:	Fab10A-SG	Fab10A-SG-Photoli 0.832456	1684454399	Operational
2025-07-17 02	2:06:	Fab10A-SG	Fab10A-SG-Photoli 0.766	7359446208	Operational
2025-07-17 02	2:16:	Fab10A-SG	Fab10A-SG-Photoli 0.7521314	4504375466	Operational
2025-07-17 02	2:26:	Fab10A-SG	Fab10A-SG-Photoli 0.7521314	4504375466	Operational
2025-07-17 02	2:36:	Fab10A-SG	Fab10A-SG-Photoli 0.7083179	9678877867	Operational
2025-07-17 02	2:46:	Fab10A-SG	Fab10A-SG-Photoli 0.7740383	1917124266	Operational
2025-07-17 02	2:56:	Fab10A-SG	Fab10A-SG-Photoli 0.766	7359446208	Operational
2025-07-17 0	3:06:	Fab10A-SG	Fab10A-SG-Photoli 0.803247	1800789333	Operational

only showing top 10 rows

SAMPLE LOT DATA:

+		+			+	+
1	timestamp]	lot_id prod	uct_line	yield	_rate qual	ity_grade
+	+	+			+	+
2025-07-17	03:26: LOT	000001 N	OR Flash 0.	87408537116	07269	В
2025-07-17	03:46: LOT	999992 N	OR Flash 0.	93511525632	68769	В
2025-07-17	04:16: LOT	00003	NAND 0.	87980146994	34422	A
2025-07-17	05:06: LOT	000004	DRAM 0.	97470321421	20775	В
2025-07-17	05:26: LOT	000005	NAND 0.	90076077353	70163	В
2025-07-17	06:06: LOT	900006 31	D XPoint	0.887933685	19939	В
2025-07-17	06:36: LOT	000007	NAND 0.	86142824216	65574	C
2025-07-17	06:56: LOT	800008	DRAM 0.	92384639544	34243	C

```
Analyzing OEE for Fab10A-SG...
   OEE Analysis for Fab10A-SG:
   Fab10A-SG - CMP: OEE=0.648 (Needs Improvement), Stability=0.113
   Fab10A-SG - Ion Implantation: OEE=0.709 (Needs Improvement), Stability=0.127
   Fab10A-SG - Etching: OEE=0.759 (Good), Stability=0.133
   Fab10A-SG - Deposition: OEE=0.727 (Needs Improvement), Stability=0.127
   Fab10A-SG - Photolithography: OEE=0.693 (Needs Improvement), Stability=0.122
   Fab10A-SG - Metrology: OEE=0.807 (Good), Stability=0.142
   Predicting yield issues for DRAM...
   Yield Prediction for DRAM:
   DRAM (20nm): Yield=91.5% (MEDIUM), Lots=57209
   DRAM (1y nm): Yield=91.5% (MEDIUM), Lots=56576
   DRAM (15nm): Yield=91.5% (MEDIUM), Lots=56646
   DRAM (1\beta nm): Yield=91.5% (MEDIUM), Lots=56793
   DRAM (1\alpha nm): Yield=91.5% (MEDIUM), Lots=56911
   DRAM (10nm): Yield=91.5% (MEDIUM), Lots=56846
    Calculating maintenance priorities...
   Maintenance Priority:
   1. Fab10A-SG-Deposition-001: CRITICAL priority (OEE: 0.748, Breakdowns: 70)
   2. Fab15-SG-Photolithography-011: CRITICAL priority (OEE: 0.684, Breakdowns: 64)
   3. Fab15-SG-Photolithography-012: CRITICAL priority (OEE: 0.682, Breakdowns: 77)
   4. Fab16-TW-Ion Implantation-011: CRITICAL priority (OEE: 0.702, Breakdowns: 54)
   5. Fab15-SG-Etching-008: CRITICAL priority (OEE: 0.760, Breakdowns: 61)
   6. Fab15-SG-Metrology-010: CRITICAL priority (OEE: 0.801, Breakdowns: 62)
   7. Fab11-US-Metrology-015: CRITICAL priority (OEE: 0.784, Breakdowns: 63)
   8. Fab10A-SG-Photolithography-008: CRITICAL priority (OEE: 0.692, Breakdowns: 68)
   9. Fab11-US-CMP-009: CRITICAL priority (OEE: 0.643, Breakdowns: 68)
   10. Fab11-US-Ion Implantation-002: CRITICAL priority (OEE: 0.728, Breakdowns: 48)
... 1. Fab10A-SG-Deposition-001: CRITICAL priority (OEE: 0.748, Breakdowns: 70)
```

```
2. Fab15-SG-Photolithography-011: CRITICAL priority (OEE: 0.684, Breakdowns: 64)
3. Fab15-SG-Photolithography-012: CRITICAL priority (OEE: 0.682, Breakdowns: 77)
4. Fab16-TW-Ion Implantation-011: CRITICAL priority (OEE: 0.702, Breakdowns: 54)
5. Fab15-SG-Etching-008: CRITICAL priority (OEE: 0.760, Breakdowns: 61)
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10. Fab11-US-Ion Implantation-002: CRITICAL priority (OEE: 0.728, Breakdowns: 48)
```

TESTING RAG SYSTEM:

 \P Processing manufacturing query: 'What are the current bottlenecks in our production line?' → Searching manufacturing context...

 \checkmark Found 5 relevant records

TESTING MANUFACTURING SKILLS:

- → Augmenting prompt with context...
- → Generating AI response...

 $\checkmark \ {\tt Response \ generated}$

Query: What are the current bottlenecks in our production line? Response: Root Cause Analysis:

1. The largest variance is seen at Fab16-TW with -14.8% suggesting that this production line is not meeting its planned output. This could be due to a lack of resources, equipment malfunctions, or inefficiencies in the production process.